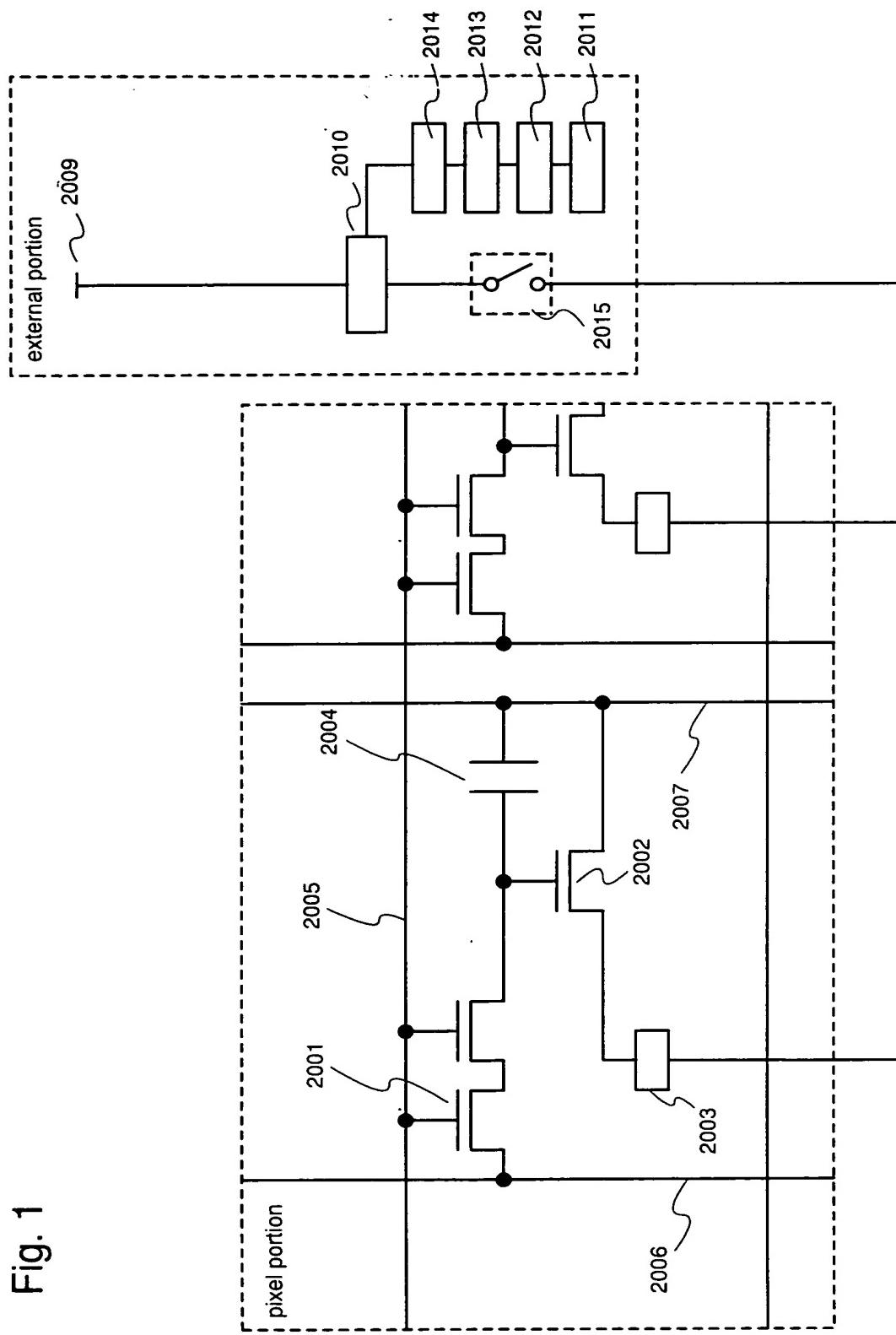


Fig. 1



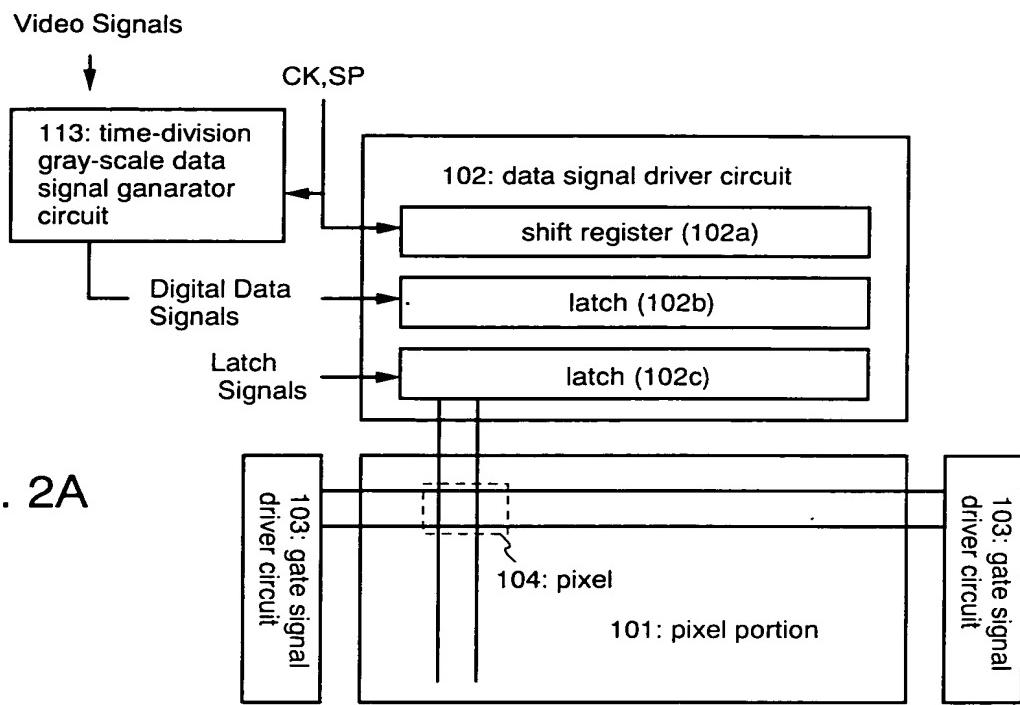


Fig. 2A

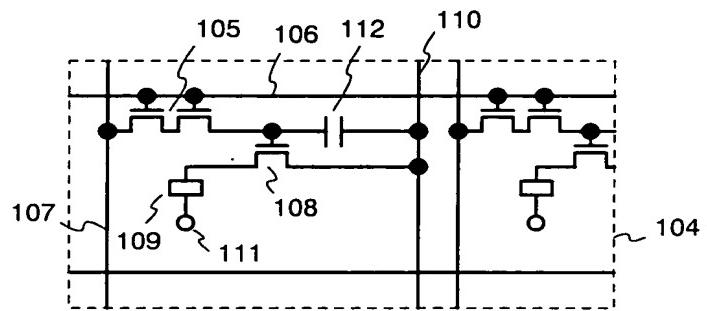


Fig. 2B

Fig. 3

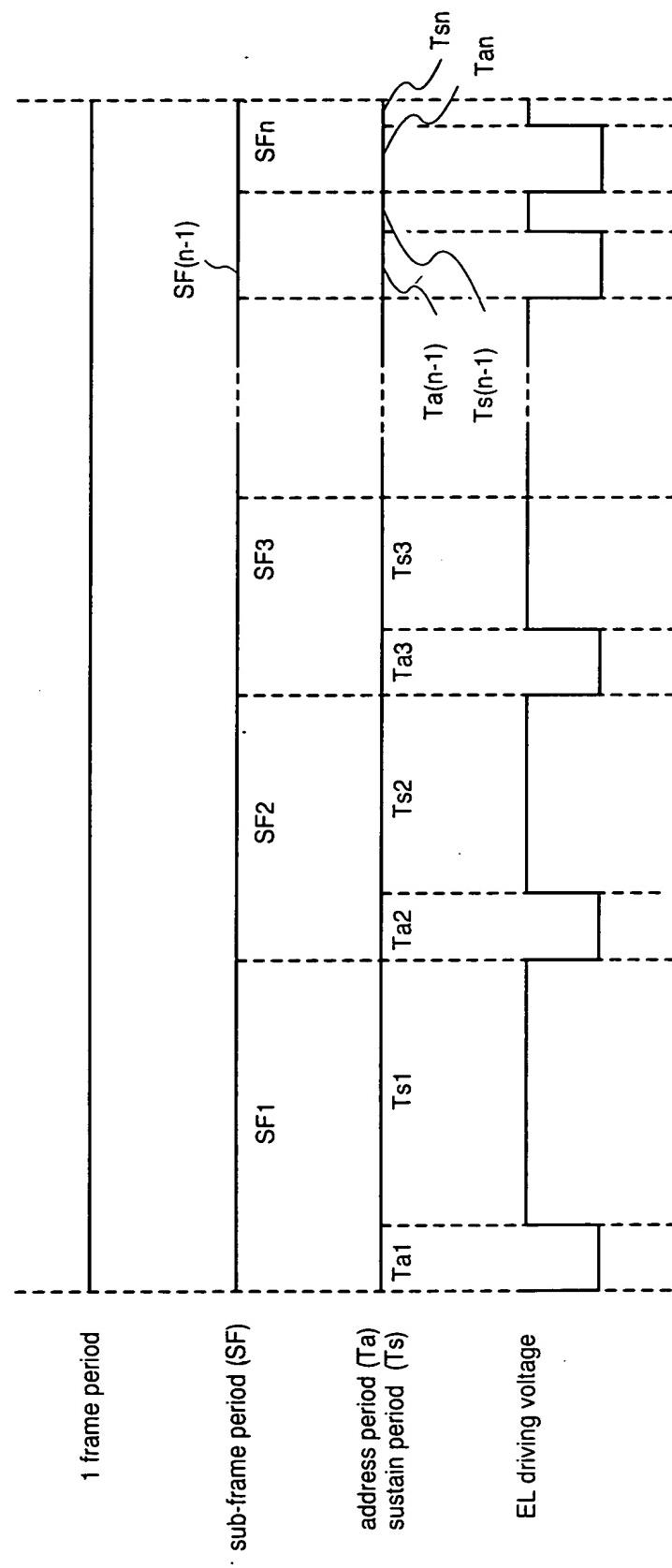


Fig. 4

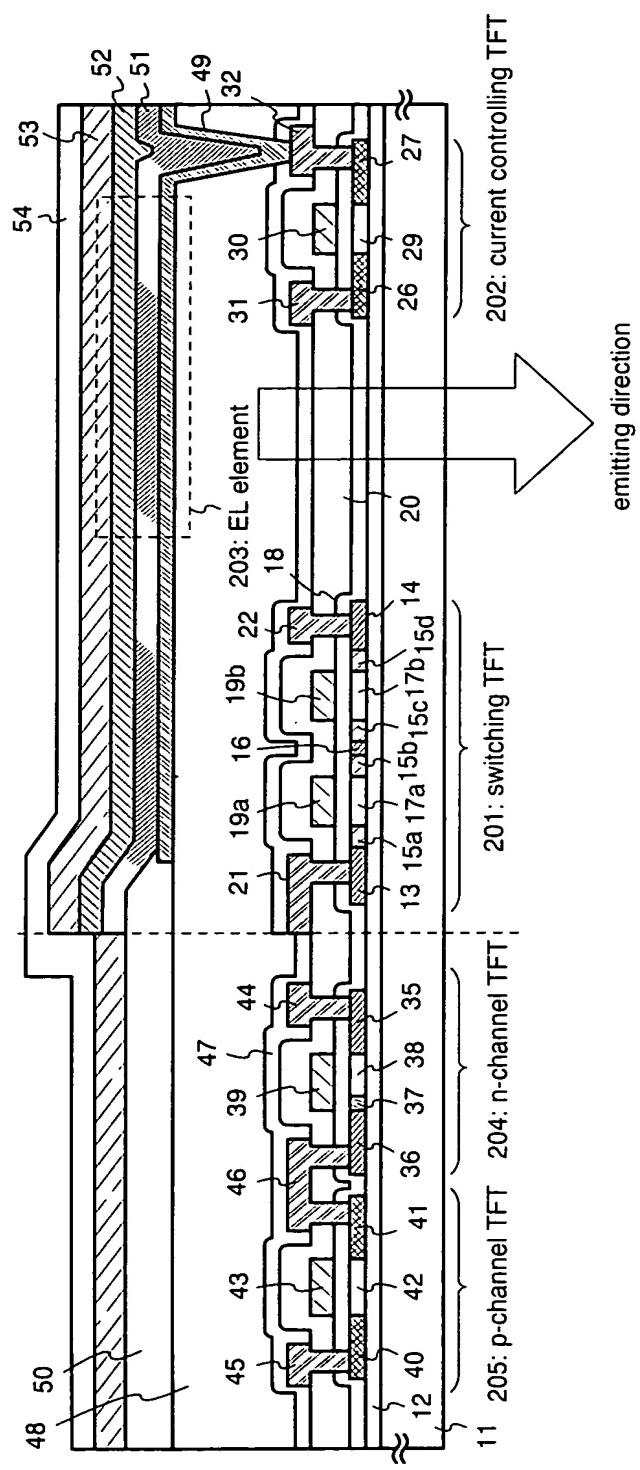


Fig. 5

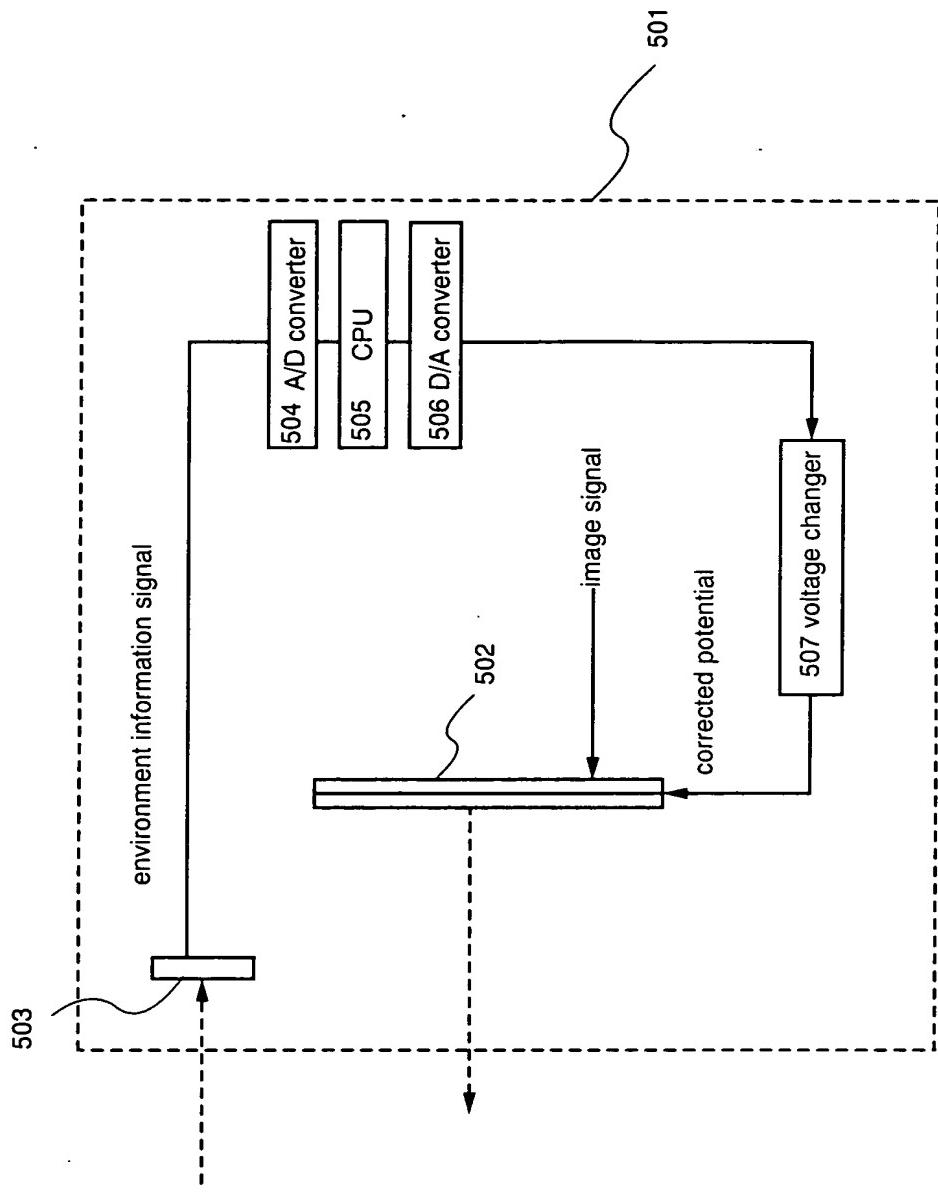


Fig. 6

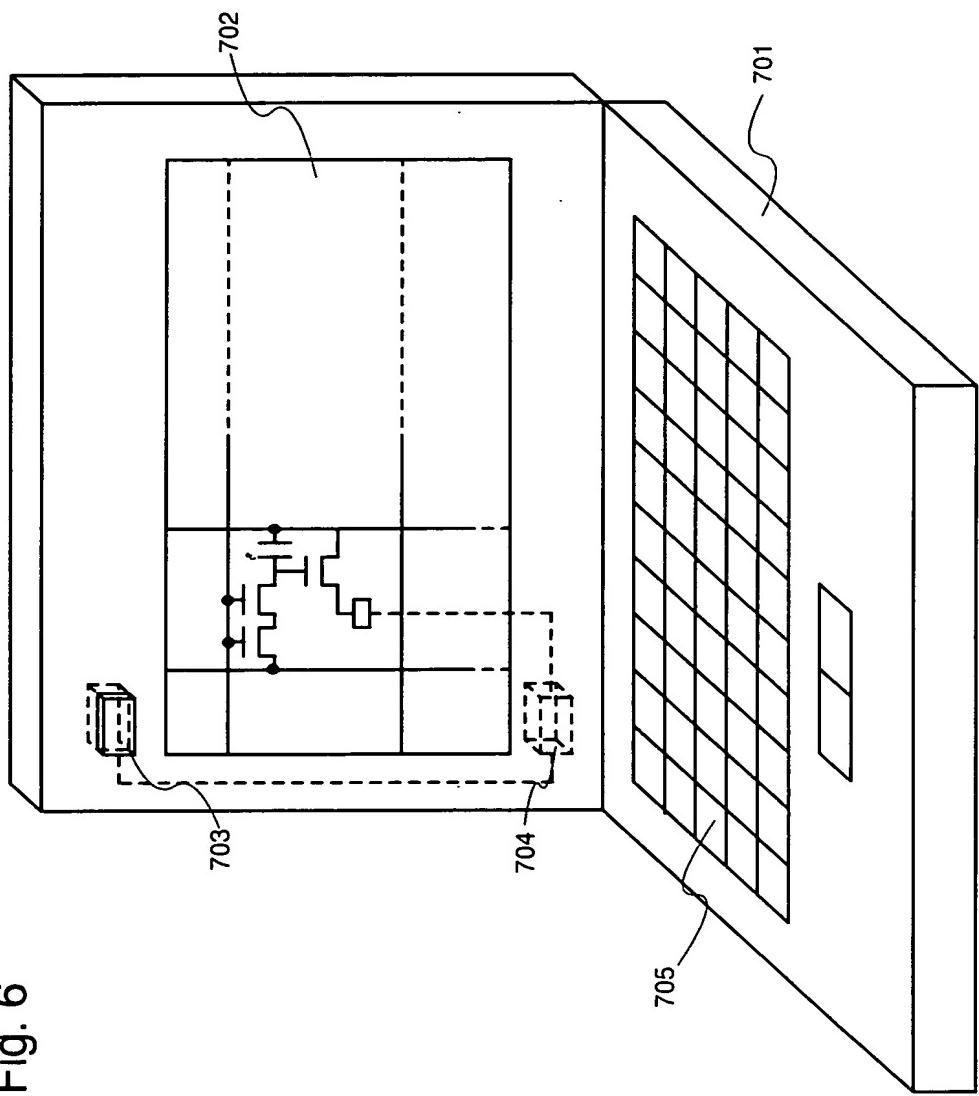


Fig. 7

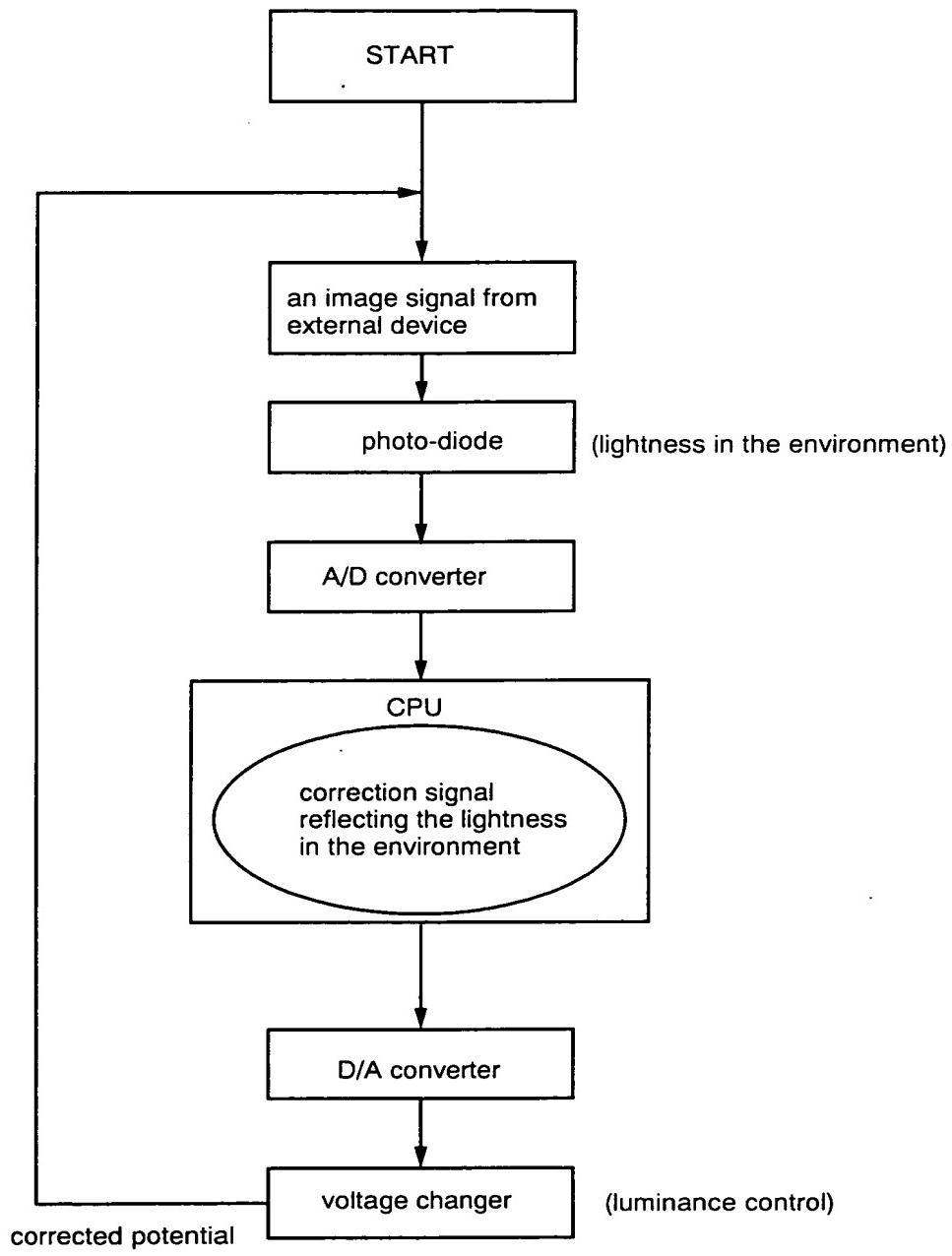
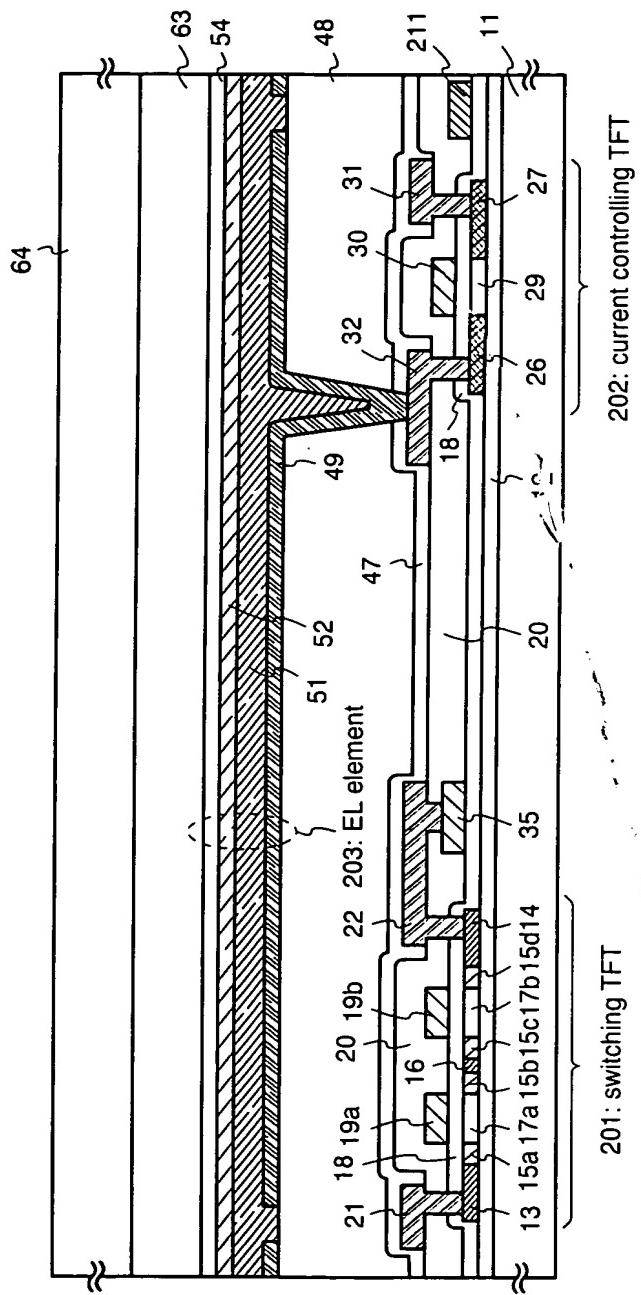


Fig. 8



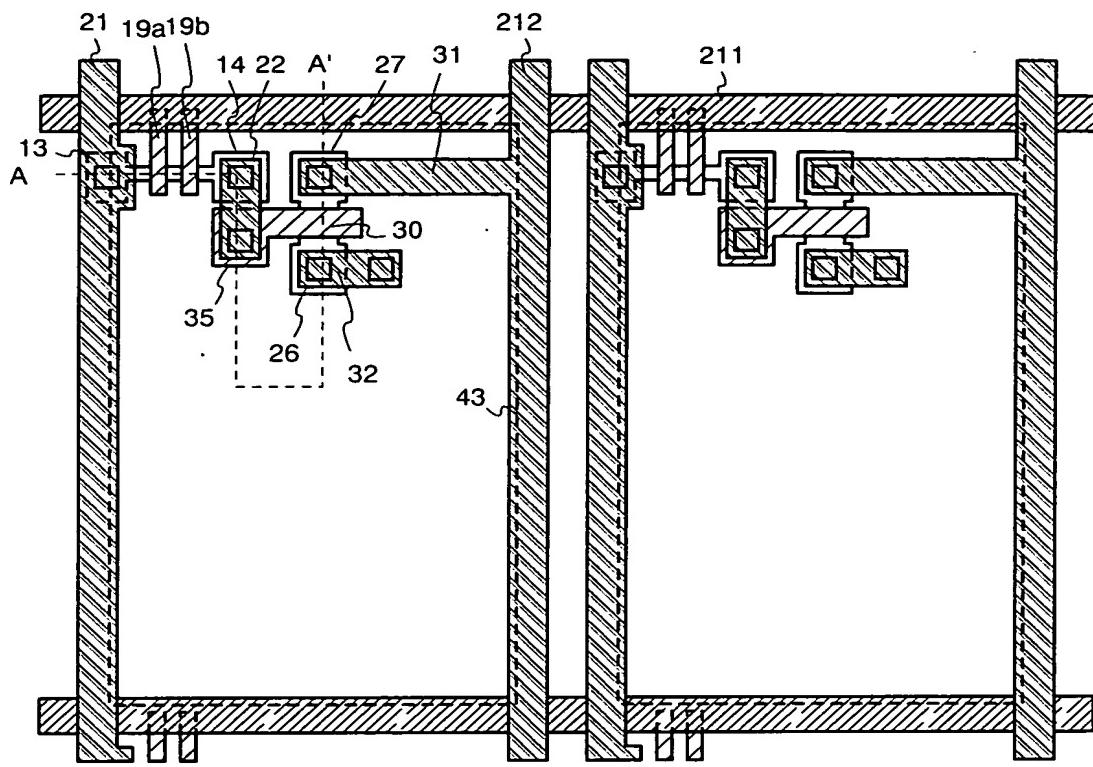


Fig. 9A

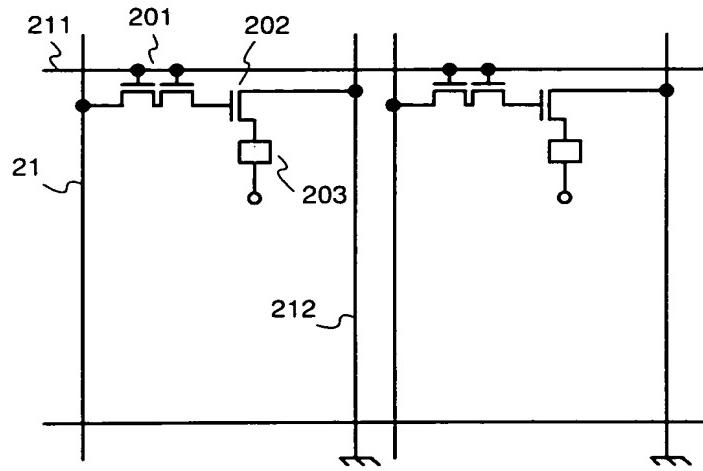


Fig. 9B

crystallization process

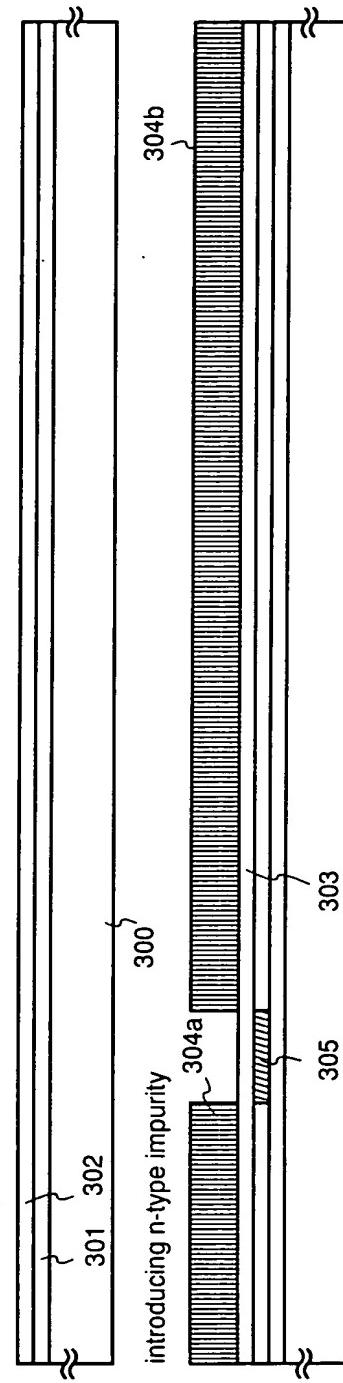


Fig. 10A

laser annealing process

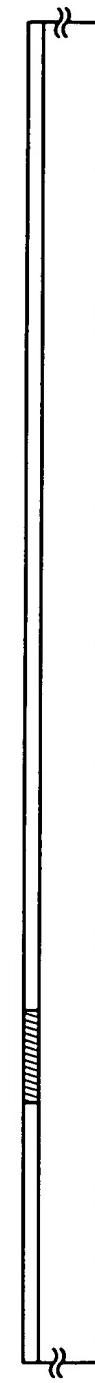


Fig. 10B

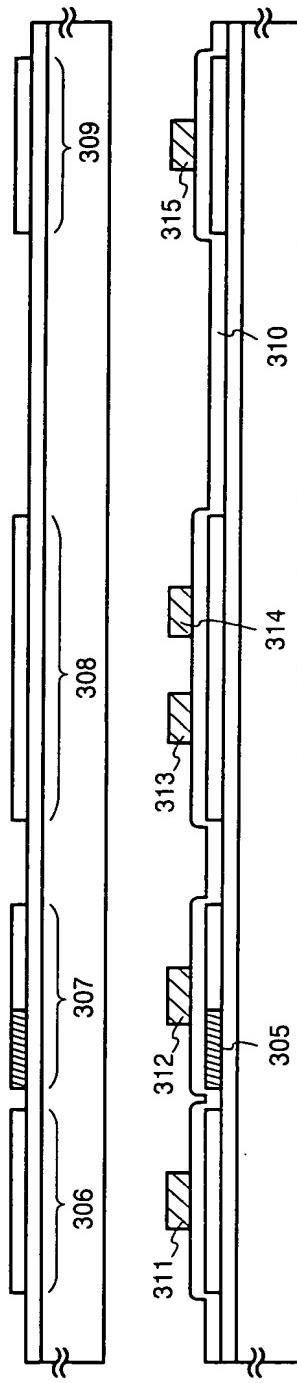


Fig. 10C

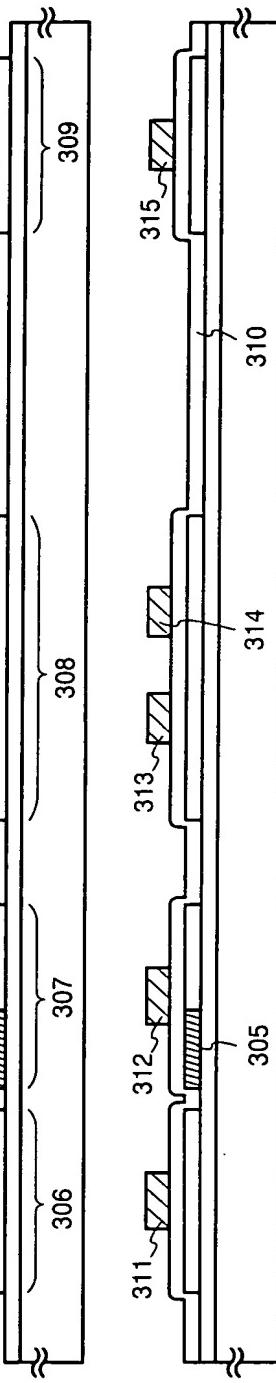


Fig. 10D

Fig. 10E

introducing n-type impurity

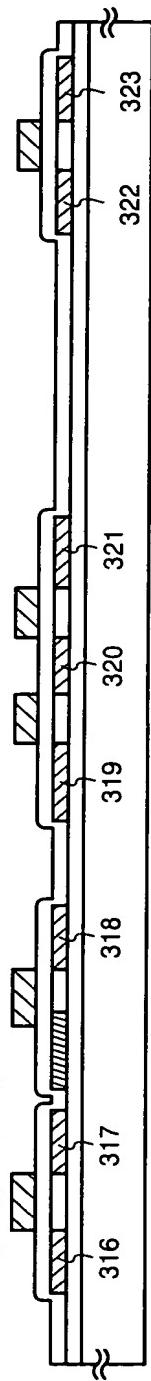


Fig. 11A

introducing n-type impurity

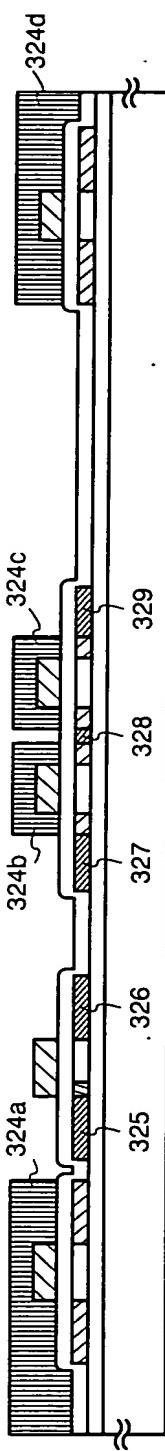


Fig. 11B

introducing p-type impurity

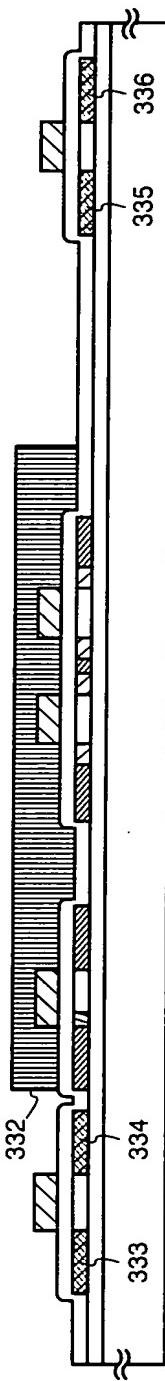


Fig. 11C

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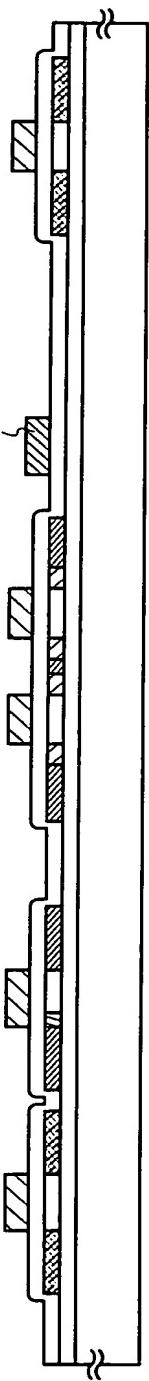


Fig. 11D

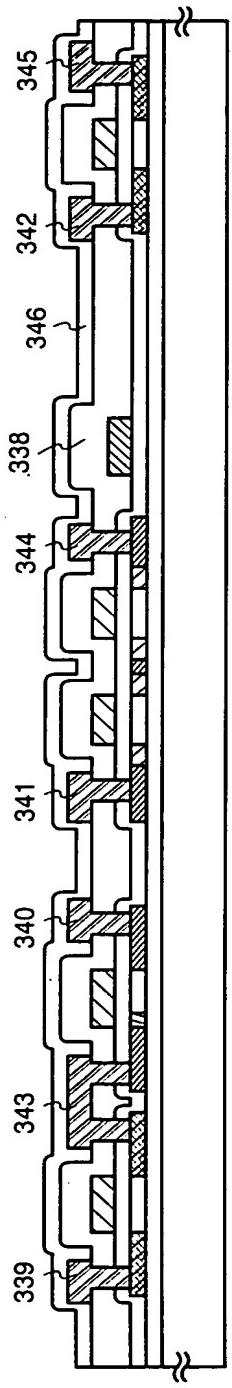


Fig. 12A

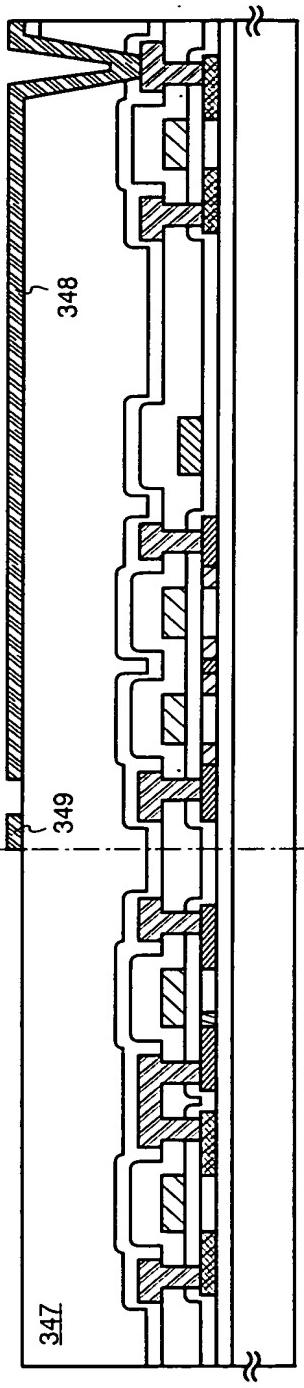


Fig. 12B

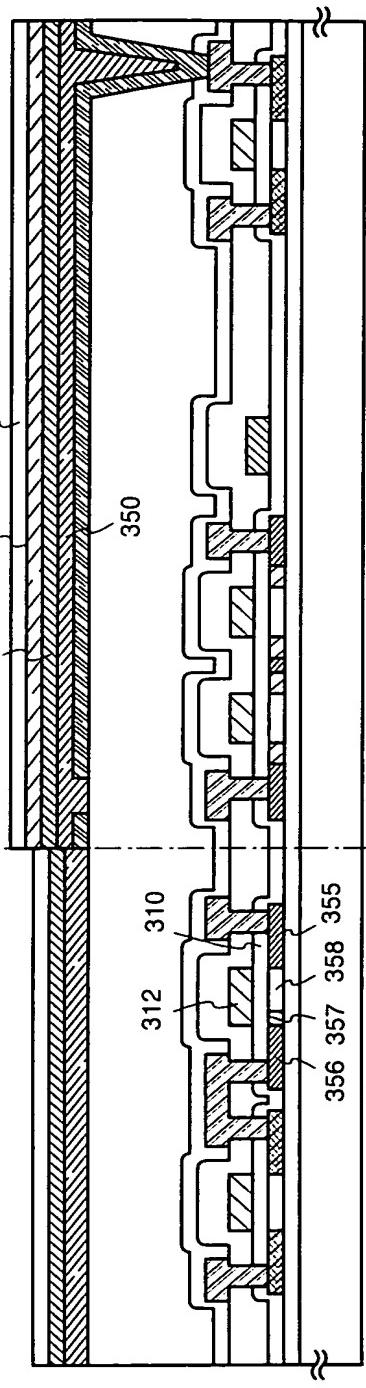


Fig. 12C

206: p-channel TFT 205: n-channel TFT

Fig. 13

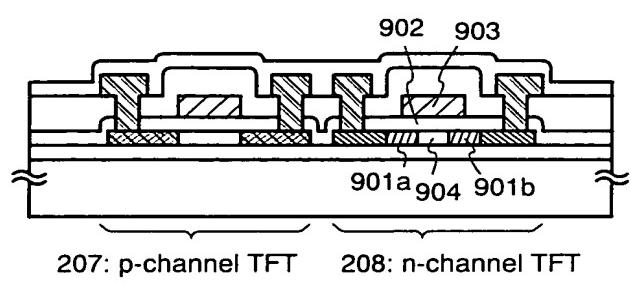
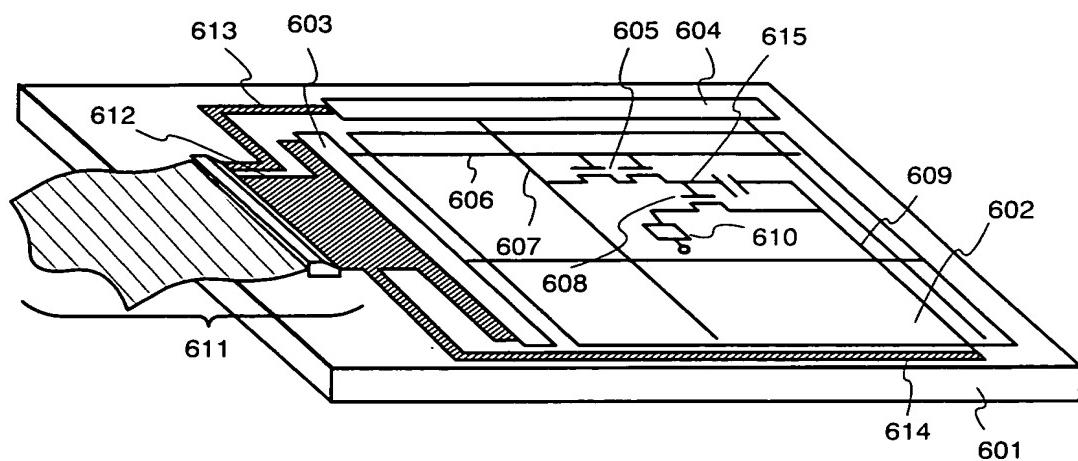


Fig. 14



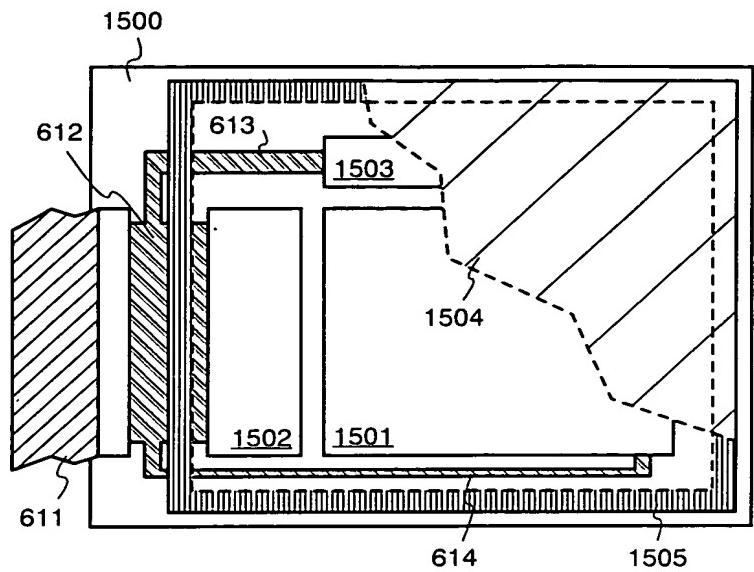


Fig. 15A

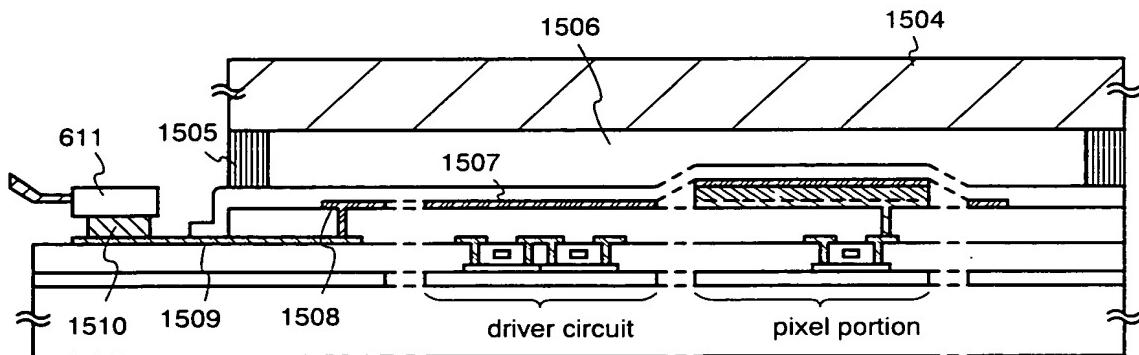


Fig. 15B

Fig. 16

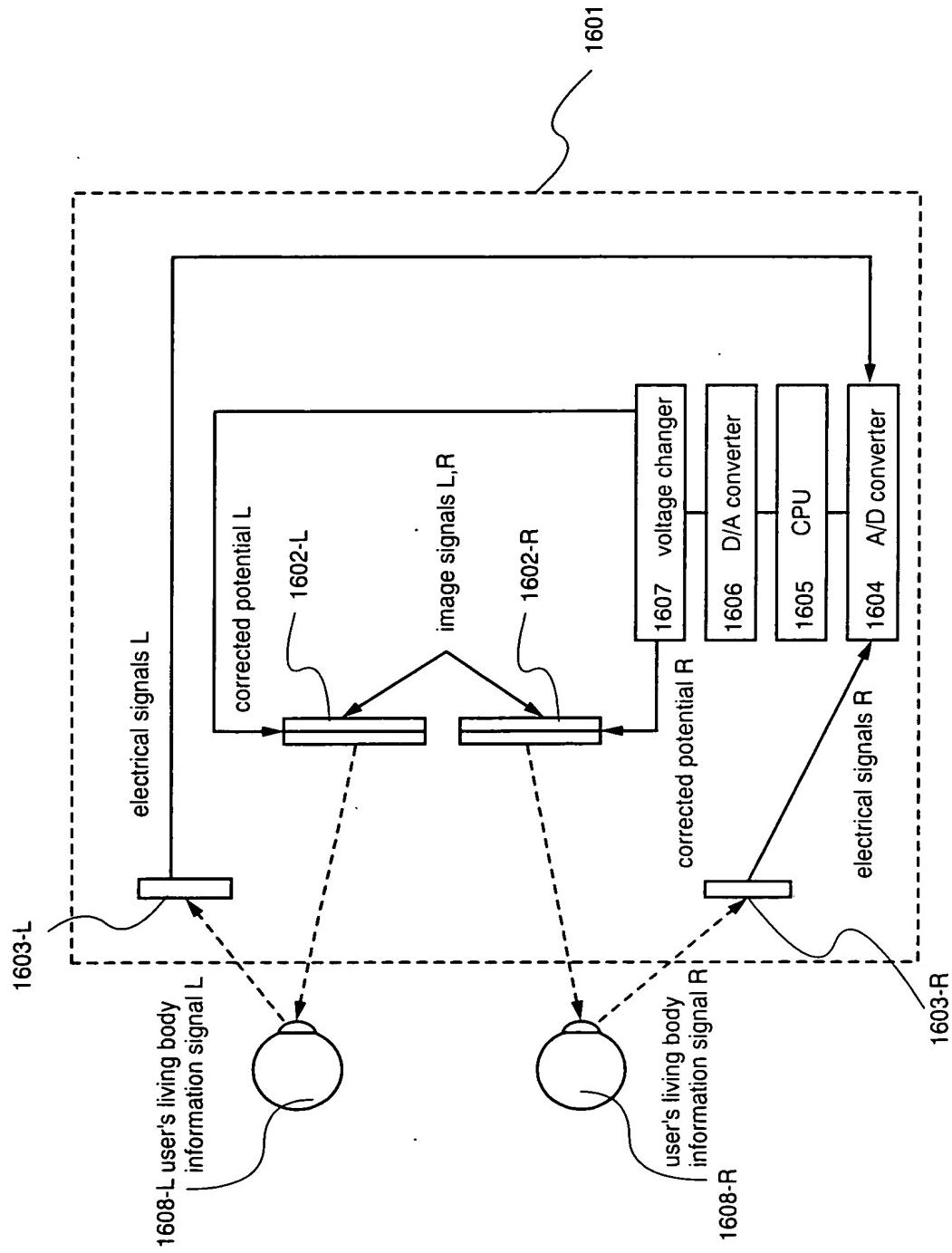


Fig. 17

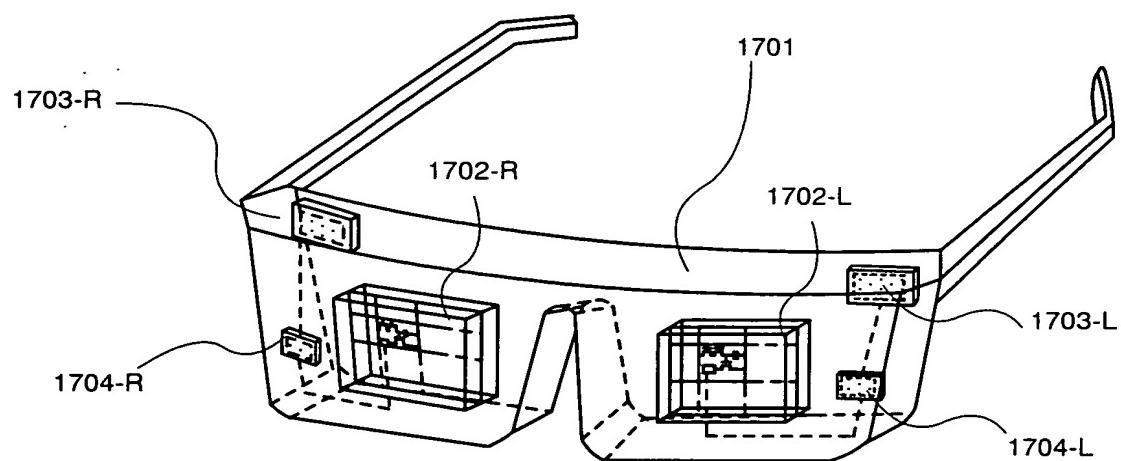


Fig. 18

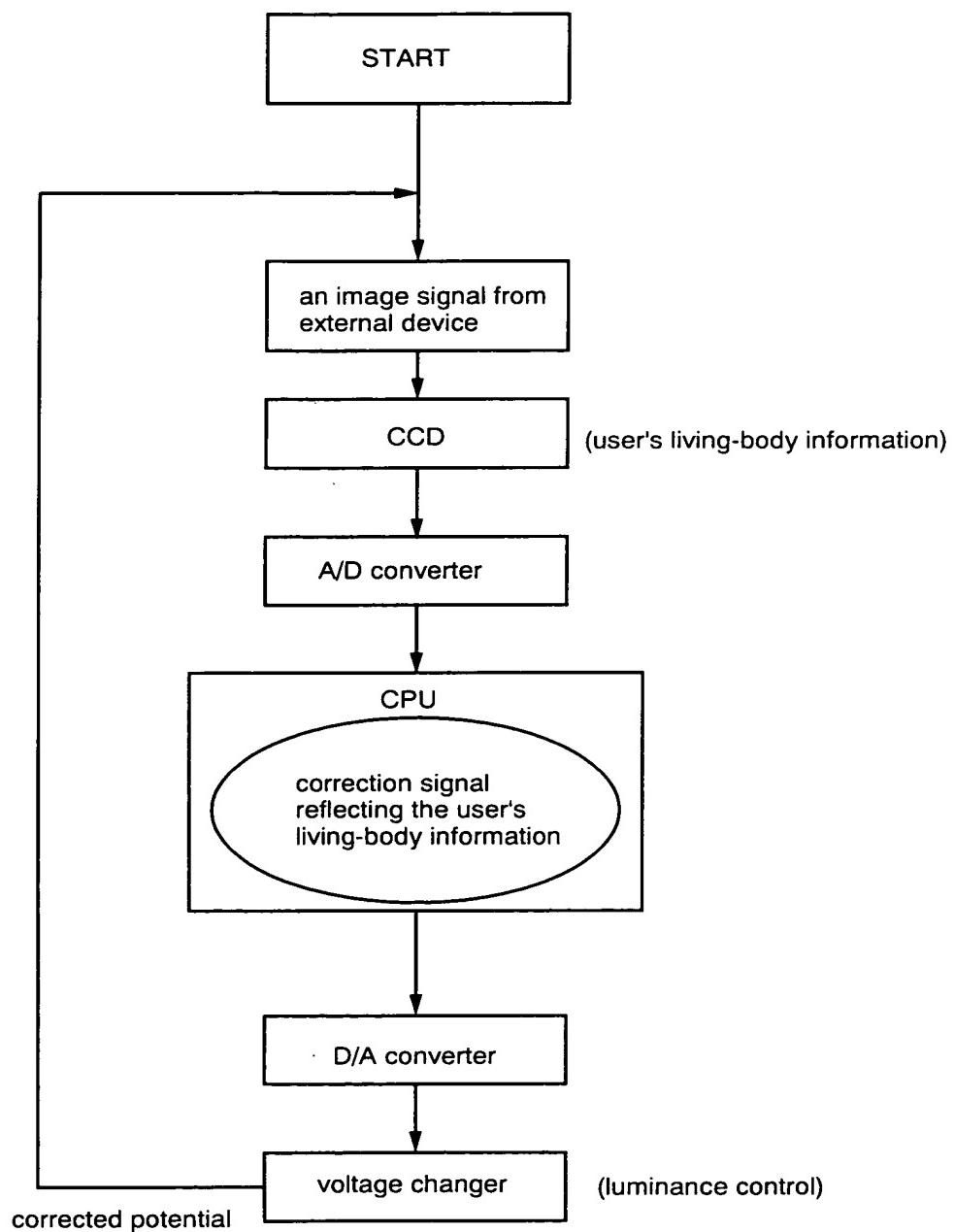


Fig. 19A

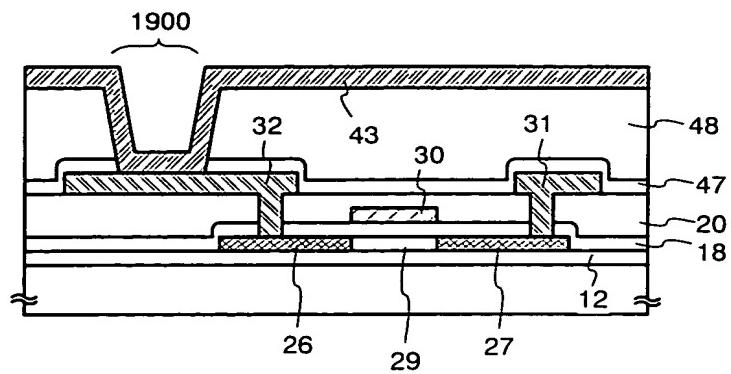


Fig. 19B

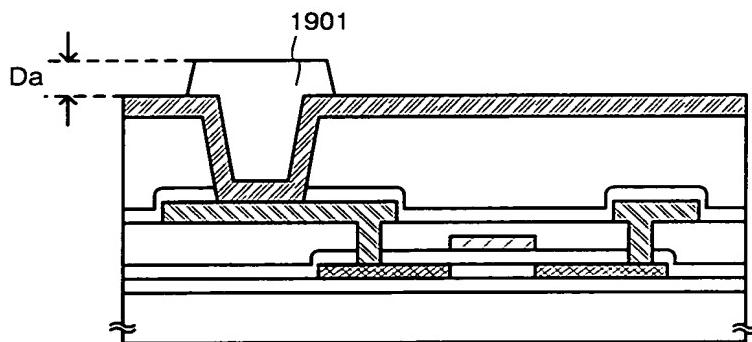
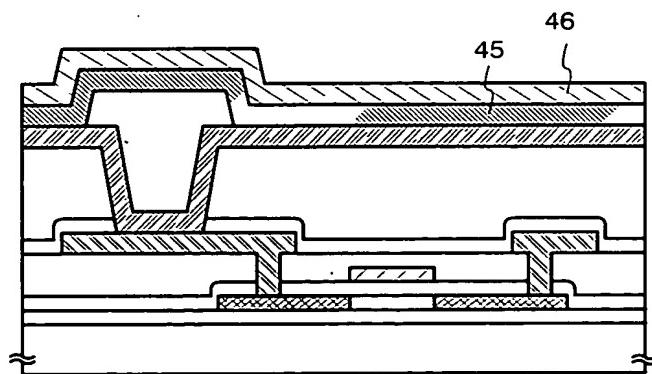


Fig. 19C



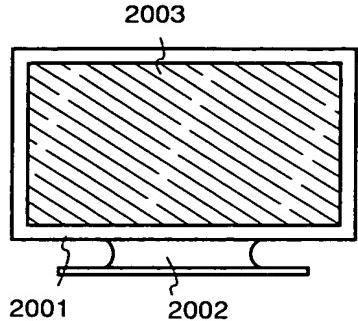


Fig. 20A

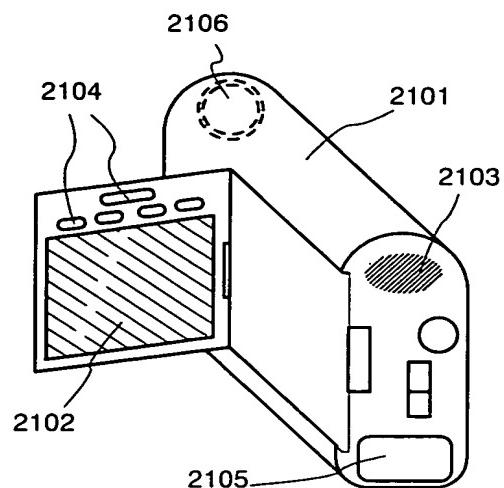


Fig. 20B

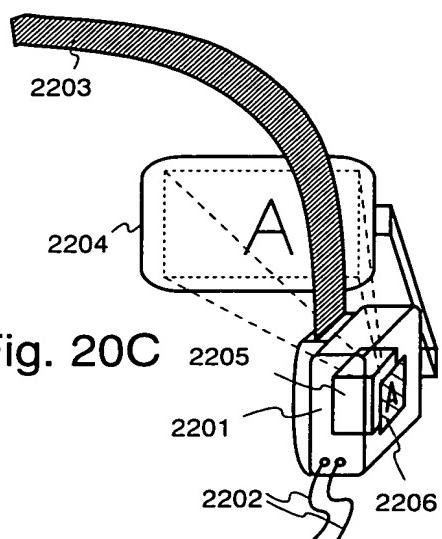


Fig. 20C

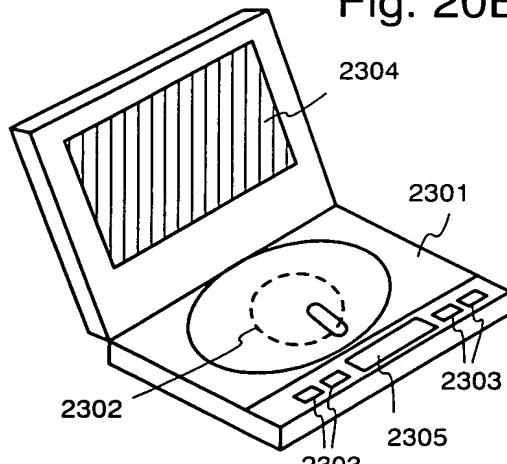


Fig. 20D

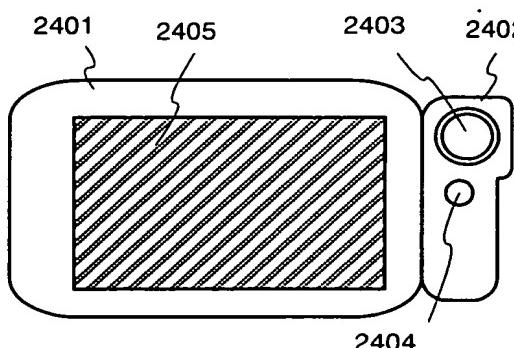


Fig. 20E

Fig. 21A

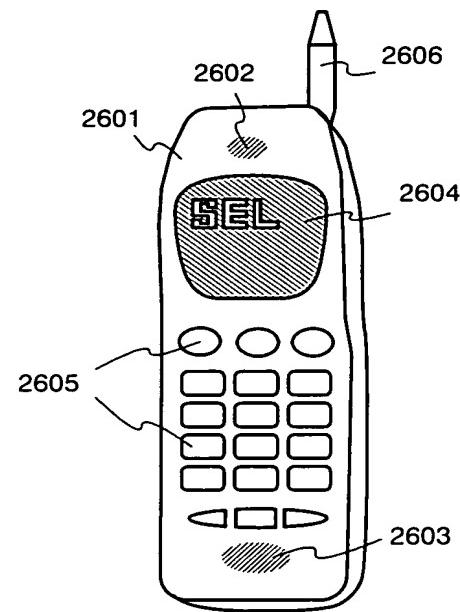


Fig. 21B

